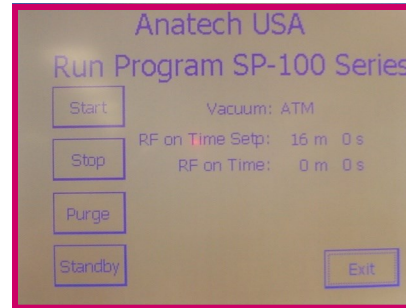


SCE-108-AL Series Plasma Systems



SCE 108-AL Plasma System



Siemens "Touch Panel" Control
Password Protected



Parallel Plate Configuration
Inside chamber view

Immersing parts in low temperature plasma may be your final cleaning solution !!

Anatech plasma systems are CFC and effluent free, operator and environmentally safe, easily operated.

- Typical uses:
- Hybrid Circuit cleaning prior to wire bonding
 - Ashing Photo resist
 - Pre-cleaning substrates prior to deposition process
 - Cleaning various materials to improve adhesion
 - Surface modification for wet ability

SCE 108-AL Box Plasma System Specifications

Control System

Siemens S7-200 series PLC controlled auto sequencing
Touch-Panel interface
On screen vacuum display –Convection gauge
Gas flow control needle valve

Options:

Mass flow controller—up to 3-gasses
Multi-color touch screen
Multiple Process PLC with recipe and & process memory

Aluminum Reactor Chamber:

Inside dimensions:
8” wide X 8” high X 10 Deep
Front load
View port in door
Standard 2 shelf operation 5” X 5” X 1.5” parts. Custom quoted upon request

RF Power Source

0-125 Watt RF 13.56 MHz supply
Manual tuning
Forward and reflected power readings

Options:

Automatic Tuning, matching network
0-300 Watt RF with auto tuner

Facility Requirements

115-VAC 20A 50/60-HZ Cabinet
115-VAC 20A 50/60-HZ Vacuum
60-PSI air
Process gas 5-8-PSI

Options:

220VAC option available

Dimensions

System size
23” W x 26” H x 30” D

Crate size 35X29X39 LWH
150 Lbs. Crated weight (estimated)

Vacuum System

3.8 CFM Standard service pumping
KF-16 Pneumatic valve for pump isolation

Options:

Oxygen service Class “B” Preparation

CALL ANATECH USA TODAY TO DISCUSS YOUR APPLICATION

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